

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-2536		SERIAL NO. 10/17.175	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Fernando Gonzalez et al.			
				FILING DATE 03/31/04		GROUP 2511	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
✓	AA	4,503,108	02/90	Young et al.			
✓	AB	6,566,210 B7	05/03	Ajmera et al.			
✓	AC	5,650,343	07/97	Lusling et al.			
✓	AD	6,106,691	10/01	Koh			
✓	AE	2001/0045604 A1	11/01	Oda et al.			
✓	AF	2001/0008292 A1	07/01	Loebandung et al.			
	AQ						
	AN						
	AI						
	AJ						
	AK						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	AL						
	AM						
	AN						
	AO						
	AP						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
✓	AR			Lee et al., "Investigation of poly-Si1-xGe2 for dual-gate CMOS Technology," IEEE Electron Device Letters, Vol. 19, No. 7, 1998, pp. 247-249.			
✓	AS			Wolf et al., "Silicon Processing for the VLSI Era Vol. 1 - Process Technology," Lattice Press, 1986, pp. 101-194.			
	AT						
EXAMINER				DATE CONSIDERED			
				3/20/05			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. M122-2536		priority SERIAL NO. 09/989,931	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT Micron Technology, Inc.			
					priority FILING DATE 11/21/01		priority GROUP 2815	
U.S. PATENT DOCUMENTS								
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate		
2	AA	6,462,381 B1	10/02	Beebe et al.				
2	AB	5,999,675	12/99	Sugiyama				
2	AC	6,555,891 B1	04/03	Furukawa et al.				
2	AD	5,891,769	04/99	Liao et al.				
2	AE	6,653,714 B2	11/03	Matsuno et al.				
2	AF	6,544,854 B1	04/03	Puchner et al.				
2	AG	6,620,671 B1	09/03	Wang et al.				
2	AH	6,358,806 B1	03/02	Puchner				
FOREIGN PATENT DOCUMENTS								
	Document Number	Date	Country	Class	Subclass	Translation		
						Yes	No	
2	AJ	JP 11-177122 A	07/99	Sugiyama				
2	AJ	JP 10270746 A	10/98	Sugiyama				
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
	AK	/						
	AL							
	AM							
	AN							
	AO							
EXAMINER				DATE CONSIDERED				
[Signature]				3/20/05				
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U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
P	AA	5,759,908	06/98	Streckl				
P	AB	2002/0019105 A1	02/02	Hattori et al.				
P	AC	2003/0162586 A1	04/03	Wallace et al.				
P	AD	2002/0182423 A1	12/02	Chu et al.				
P	AE	2002/0086557 A1	07/02	Matsumura et al.				
	AF							
	AG							
	AH							
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
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	AJ							
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	AL							
	AM							
	AN							
EXAMINER				DATE CONSIDERED				
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